

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Katsuyoshi MATSUURA, et al.

Serial No.

Filed: January 4, 2001

Title: SEMICONDUCTOR DEVICE HAVING A
FERROELECTRIC CAPACITOR AND A
FABRICATION PROCESS THEREOF

Examiner:

Art Unit:

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Please enter the following amendment to the specification filed in the present case:

IN THE SPECIFICATION:

Please amend the first full paragraph at page 1, lines 6-8, to include a reference to all the priority applications, as follows (clean copy attached):

The present invention is a continuation application of co-pending U.S. Patent Application Serial No. 09/551,233 filed April 17, 2000, which is a continuation-in-part application of [the] United States patent application 09/429,984 filed on October 29, 1999.

IN THE CLAIMS:

Please cancel claim 3.

Please amend claims 1, 7 and 15 as follows (clean copy attached):

1. (Amended) A method of fabricating a semiconductor device having a ferroelectric capacitor, comprising the steps of:
forming an active device element on a substrate;